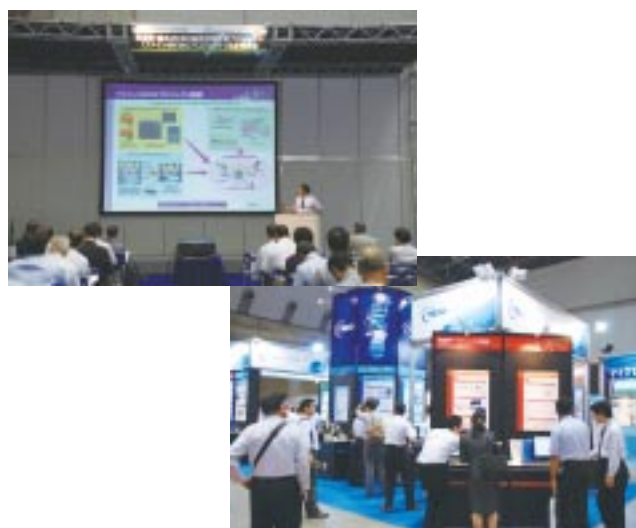


Activities of the MEMS System Development Center

1. Presentation of Results from the Fine MEMS Project and Activities for Disseminating MEMSPedia

A meeting for presenting the results from the Highly Integrated, Complex MEMS Production Technology Development Project (the Fine MEMS Project) commissioned and subsidized by the New Energy and Industrial Technology Development Organization (NEDO) was held on July 31 (Friday) in a special conference room set up within East Hall 5 of Tokyo Big Sight as part of the MicroNano 2009 event (sponsored by NEDO and cosponsored by METI). The meeting began with opening remarks from the sponsor given by Katsuya Okano, head of the Machinery System Technology Development Department at NEDO, and was followed by a guest speech by Motoki Korenaga, Deputy Director of the Industrial Machinery Division under METI's Manufacturing Industries Bureau. Next, Dr. Isao Shimoyama, project leader of the Fine MEMS Project and professor of the Graduate School of Information, Science, and Technology, the University of Tokyo, gave an overview of achievements made through the Fine MEMS Project. Thereafter, the individual leaders for each of the nine commissioned projects and the eight subsidized projects gave a detailed report on their own project achievements, which led to much lively discussion. As was the case with last year's meeting for presenting the interim achievements, this year's meeting proved to be quite popular, with a large enough audience to fill most of the approximately 200-person-capacity hall and to exhaust all 400 copies of the prepared material handouts.

Similarly, NEDO's booth on the Fine MEMS Project at the exhibition center attracted a large number of visitors and also served as a place for more in-depth and animated discussion on the presentation of results. Panel exhibits and computer demonstrations were provided at both the NEDO booth and the Micromachine Center booth on the knowledge database and MEMS equivalent circuit generator, which the Micromachine Center made available to the public in June 2009 under the name MEMSPedia. There was a lot of positive feedback on MEMSPedia, with many visitors looking forward to further developments and expanded functions in the tool.



Presentation of the Fine MEMS Project (upper left) and MEMSPedia demonstrations

The enthusiastic atmosphere at the conference hall throughout the presentation of results and the exhibition showed a strong interest in the achievements of this project. We hope that more companies will utilize this data for commercial products and that the project will lead to new collaborations.

Information on all of the activities in the project performed thus far, materials prepared for the presentation of results, and NEDO reports are available via the Fine MEMS Project link provided on the Micromachine Center's home page. Feel free to make use of these materials.



Web page for the Fine MEMS Project

2. Nano-Tech R&D Base, Tsukuba

METI's policy measures for strengthening the role of AIST Tsukuba Central as an R&D base for nanotechnology have entered the implementation stage. The measures call for more emphasis on N/MEMS, as well as nanoelectronics and power electronics. The policy sets a new direction that will not only enhance MEMS R&D at the arena, but also initiate implementation of the arena as a center for trial manufacturing, with the Micromachine Center playing an active role in planning the specifics. In addition to cutting-edge technologies emphasizing multilayer integration, large-diameter wafers, and low environmental impact, the MMC recognizes the importance of a trial production line that facilitates the transition to mass production and is investigating this possibility. We will be providing more information as the investigation progresses.